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<p>Substitute for form 1449A/PTO</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(use as many sheets as necessary)</p>				COMPLETE IF KNOWN			
				Application Number	09/888,002		
				Confirmation Number	9049		
				Filing Date	June 21, 2001		
				First Named Inventor	Whonchee Lee		
				Group Art Unit	3723		
Examiner Name							
Sheet	1	of	1	Attorney Docket No.	108298515US3		
U.S. PATENT DOCUMENTS							
EXAMINER INITIALS	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
		NUMBER	Kind Code (if known)				
DVN	AA	6,176,992✓		Talieh	1/23/01		
	AB	5,930,699✓		Bhatia	7/27/99	TC 3 311 111	
↓	AC	5,807,165✓		Uzoh et al.	9/15/98	TC 3 311 111	
	AD					TC 3 311 111	
	AE					TC 3 311 111	
	AF					TC 3 311 111	
	AG					TC 3 311 111	
	AH					TC 3 311 111	
	AI					TC 3 311 111	
	AJ					TC 3 311 111	
FOREIGN PATENT DOCUMENTS							
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OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS							
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DVN	AP	SEILCHI KONDO, NORIYUKI SAKUMA, YOSHIO HOMMA, YASUSHI GOTO, NAOFUMI Ohashi, Hizuru Yamaguchi, and Nobuo Owada, "Abrasive-Free Polishing for Copper Damascene Interconnection", <i>Journal of the Electrochemical Society</i> , 147 (10) 3907-3913 (2000)✓					
	AQ						
	AR						
EXAMINER <i>Sung van Hyun</i>				DATE CONSIDERED 11-27-2002			
<p>* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).</p>							